

APPARATUS WITH PROCESSING STATIONS FOR MANUALLY AND AUTOMATICALLY PROCESSING MICROELECTRONIC WORKPIECES

ABSTRACT OF THE DISCLOSURE

A method and apparatus for manually and automatically processing microelectronic workpieces. The apparatus can include a tool having a plurality of processing stations, all of which are manually accessible to a user, and an input/output station configured to support at least one microelectronic workpiece for automatic transfer to and from the processing stations. A transfer device is positioned proximate to the input/output station and the processing stations and is configured to automatically transfer microelectronic workpieces between the input/output station and the processing stations. The apparatus can be used for both manual and automatic processing of microelectronic workpieces, either sequentially or simultaneously. The processing stations can be configured to perform on the microelectronic workpiece functions such as material application, material removal, seed layer enhancement, rinsing, drying, annealing, baking, and metrology.